Chapter 16-3. MOS C-V characteristics

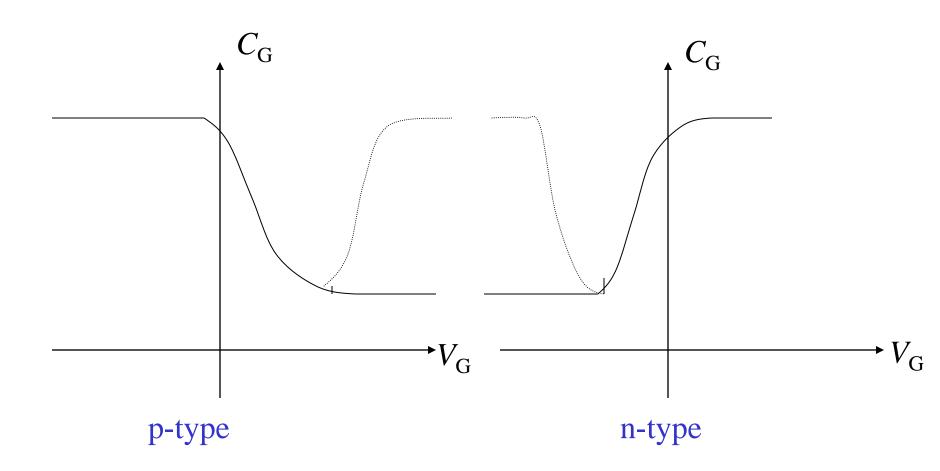
The measured MOS capacitance (called gate capacitance) varies with the applied gate voltage

- A very powerful diagnostic tool for identifying any deviations from the ideal in both oxide and semiconductor
- Routinely monitored during MMOS device fabrication

Measurement of C-V characteristics

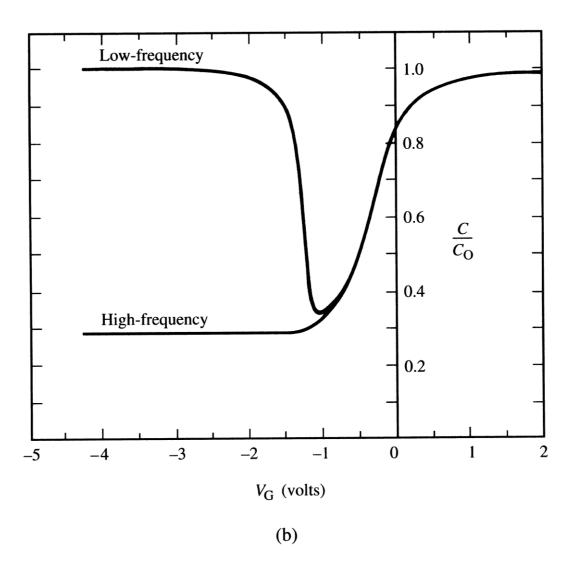
- Apply any dc bias, and superimpose a small (15 mV) ac signal
- Generally measured at 1 MHz (high frequency) or at variable frequencies between 1KHz to 1 MHz
- The dc bias V_G is slowly varied to get **quasi-continuous** C-V characteristics

C-V characteristics of MOS-capacitor on p- and n-type Si



The *C-V* data depends on the measurement frequency as well. The dotted line represents the low-frequency *C-V* data.

Measured C-V characteristics on an n-type Si



$$N_{\rm D} = 9.0 \times 10^{14} \, \rm cm^{-3}$$

 $x_{\rm ox} = 0.119 \, \mu \rm m$

Figure 16.11

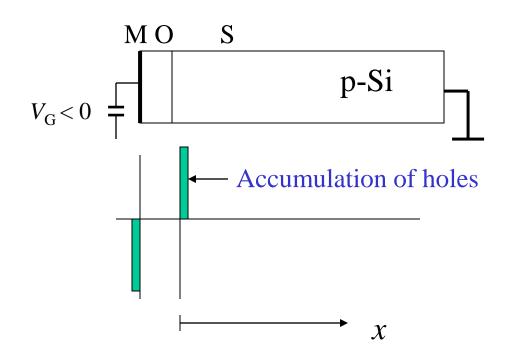
MOS-capacitor under accumulation

Consider p-type Si under accumulation.

$$V_{\rm G}$$
 < 0.
Looks similar to parallel plate capacitor.

$$C_{\rm G} = C_{\rm ox}$$

where
$$C_{\text{ox}} = (\varepsilon_{\text{ox}} A) / x_{\text{ox}}$$



Thus, for all accumulation conditions, the gate capacitance is equal the oxide capacitance.

MOS-capacitor under depletion

Depletion condition:

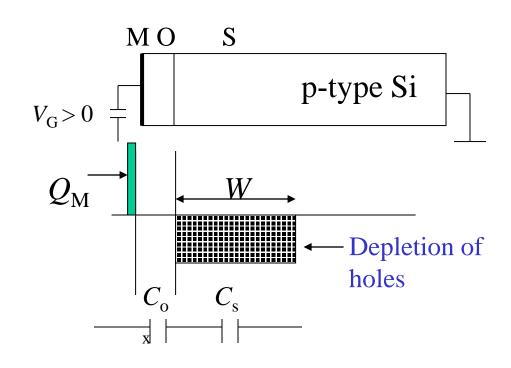
$$V_{\rm G} > 0$$

 C_G is C_{ox} in series with C_s where C_s can be defined as "semiconductor capacitance"

$$C_{\text{ox}} = \varepsilon_{\text{ox}} A / x_{\text{ox}}$$

$$C_{\text{s}} = \varepsilon_{\text{Si}} A / W$$

$$C_{\text{G}} = C_{\text{ox}} C_{\text{s}} / (C_{\text{ox}} + C_{\text{S}})$$



$$W = \sqrt{\frac{2\varepsilon_{\rm Si}}{qN_{\rm A}}\phi_{\rm S}}$$

where ϕ_s is surface potential

In this case, the gate capacitance decreases as the gate voltage is increased. Why?

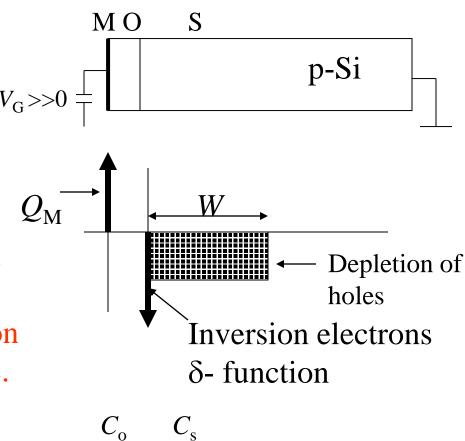
MOS-capacitor under inversion

$$V_{\rm G} = V_{\rm T}$$
 and $V_{\rm G} > V_{\rm T}$
Inversion condition $\phi_{\rm s} = 2 \ \phi_{\rm F}$

$$W = W_{\rm T} = \sqrt{\frac{2 \, \varepsilon_{\rm Si}}{q \, N_{\rm A}}} \, 2 \phi_{\rm F}$$

At high frequency, inversion electrons are not able to respond to ac voltage. So, to balance the charge on the metal, the depletion layer width will vary with the ac.

$$C_{\text{ox}} = \varepsilon_{\text{ox}} A / x_{\text{ox}}$$
 $C_{\text{s}} = \varepsilon_{\text{Si}} A / W_{\text{T}}$
 $C_{\text{G}} (\omega \rightarrow \infty) = C_{\text{ox}} C_{\text{s}} / (C_{\text{ox}} + C_{\text{S}})$



$$C_{\rm o}$$
 $C_{\rm s}$

MOS-capacitor under inversion

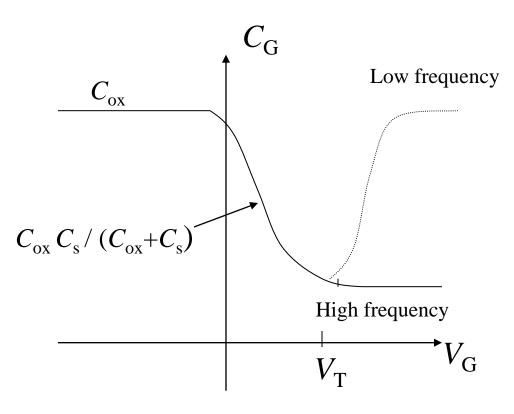
At low frequency, the inversion electrons will be able to respond to the ac voltage (Why?). So, the gate capacitance will be equal to the "oxide capacitance" (similar to a parallel plate capacitance).

$$C_{\rm G} (\omega \to 0) = C_{\rm ox}$$

= $\varepsilon_{\rm ox} A / x_{\rm ox}$

For $V_G > V_T$, the high frequency capacitance remains constant. Why?

Study exercise 16.4 in text



p-type Si

Example 1

Consider p-type silicon doped with $N_A=10^{16}$ cm⁻³. The oxide thickness is 100 nm. Plot the C_G vs. V_G characteristics when V_G is varied **slowly** from -5 V to +5 V. Assume MOS has area of 1 cm².

Find
$$C_{\text{ox}}$$
. $C_{\text{ox}} = \frac{3.9 \times 8.9 \times 10^{-14} (\text{As/Vcm})}{1000 \times 10^{-8} \text{cm}} \times 1 \text{cm}^2 = 3.47 \times 10^{-8} \text{F}$

Find C_s (min) when $W = W_T$ (Note that C_s decreases as the depletion layer width increases. It is minimum when the depletion layer width is maximum, i.e. when $W = W_T$).

$$W_{\rm T} = \sqrt{\frac{2 \times 11.9 \times 8.85 \times 10^{-12} \,\text{As/(Vm)}}{1.6 \times 10^{-19} \,\text{C} \times 10^{16} \,\text{cm}^{-3}}} \times 2 \times 0.357 \,\text{V} = 0.298 \,\mu\text{m}$$

$$C_{\rm S}(\text{min}) = \frac{10^{-12} \text{As/(Vcm)}}{0.298 \times 10^{-4} \text{cm}} \times 1 \text{cm}^2 = 3.35 \times 10^{-8} \text{F}$$

$$C_{\rm G}({\rm min}) = (3.47 \times 10^{-8} \times 3.35) / (3.47 + 3.35) \,{\rm F} = 1.7 \times 10^{-8} \,{\rm F}$$

Example 1 (continued)

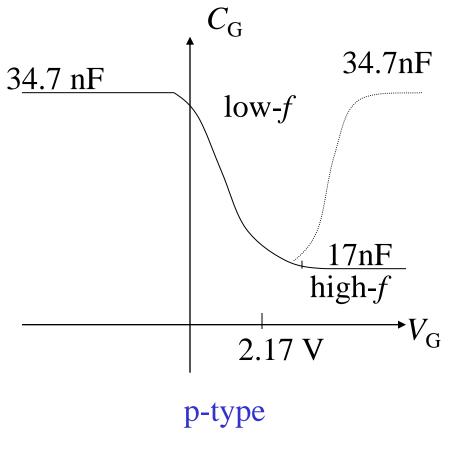
$$V_{\rm G} = V_{\rm T} = \phi_{\rm s} + x_{\rm ox} \frac{\varepsilon_{\rm Si}}{\varepsilon_{\rm ox}} \sqrt{\frac{2qN_{\rm A}}{\varepsilon_{\rm Si}}} \phi_{\rm s}$$
 when $\phi_{\rm s} = 2\phi_{\rm F}$
= 2.15 V

Plot the C-V characteristics

Explain why C_G does not vary for $V_G > V_T$

Question: How will you calculate C_G when $V_G = 1$ V?

Answer: Calculate ϕ_s when $V_G = 1$ V using the eqn. above. From ϕ_s find W, then calculate C_s . Then, calculate $C_G = (C_{ox} C_s) / (C_{ox} + C_s)$



MOS-capacitor characteristics: Deep depletion

The previous discussions pertain to the condition when the gate voltage is ramped **slowly**, from accumulation condition to depletion and then to inversion condition. When the ramp rate is high, the inversion layer does not form and does not have time to equilibrate. This is called "deep depletion" condition. In this case, W will continue to increase beyond W_T and C_G will continue to decrease as shown when the dc bias is varied from accumulation bias to deep depletion bias.

To calculate W under deep depletion condition, invert the $V_{\rm G}$ versus $\phi_{\rm s}$ relationship. Solve for $\phi_{\rm s}^{1/2}$ and hence $\phi_{\rm s}$. Then, calculate W using W versus $\phi_{\rm s}$ relationship.

Some observations

- $V_{\rm T}$ = gate voltage required for start of inversion
 - = (+) for p-type Si
 - = (-) for n-type Si

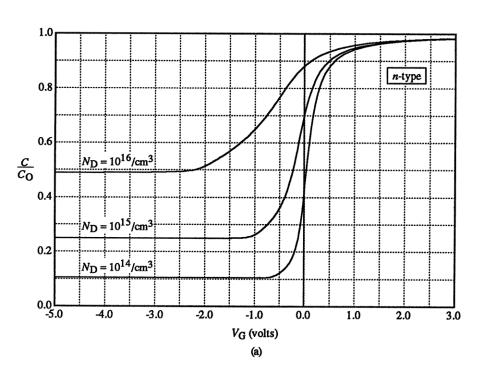
$$V_{\rm T} = 2\phi_{\rm F} + \left(\pm x_{\rm ox} \frac{\varepsilon_{\rm Si}}{\varepsilon_{\rm ox}} \sqrt{\frac{2qN_{\rm A}}{\varepsilon_{\rm Si}}} |2\phi_{\rm F}| \right)$$

$$(+) \qquad (+) \qquad (+) \qquad - \qquad \text{for p-type Si}$$

$$(-) \qquad (-) \qquad - \qquad \text{for n-type Si}$$

- Higher the doping, higher the $|V_T|$ value
- $C_{\text{max}} = C_{\text{ox}}$ and $C_{\text{min}} = C_{\text{ox}} C_{\text{s}} / (C_{\text{ox}} + C_{\text{s}})$
- Lower the doping, lower $C_{\rm s}$ and hence lower $C_{\rm min}$

Doping dependence of MOS-capacitor high frequency C-V characteristics, with $x_{ox} = 0.1 \mu m$



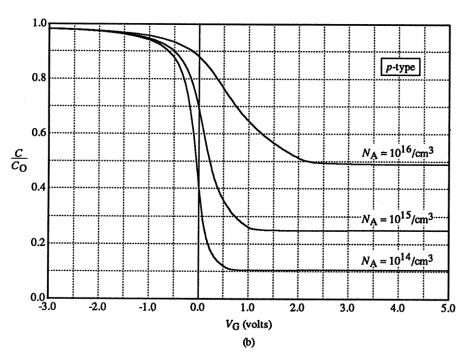


Figure 16.14

MOS-capacitor under deep depletion

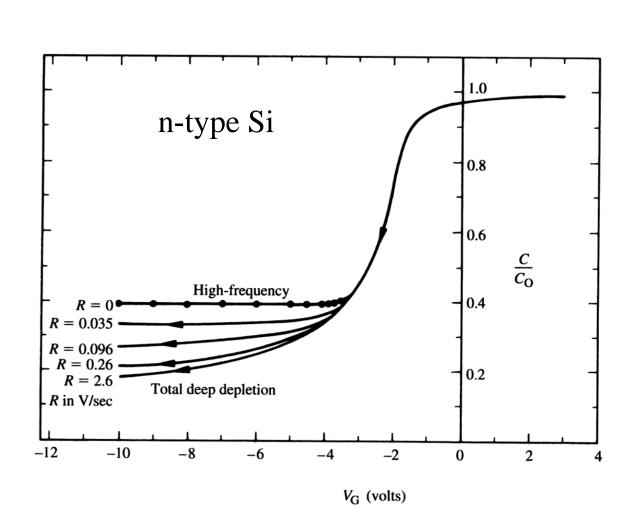
$$V_{\rm G} = \phi_{\rm S} + x_{\rm ox} \frac{\varepsilon_{\rm Si}}{\varepsilon_{\rm ox}} \sqrt{\frac{2qN_{\rm A}}{\varepsilon_{\rm Si}}} \phi_{\rm S}$$

$$W = \sqrt{\frac{2 \varepsilon_{\rm Si}}{q N_{\rm A}}} \, \phi_{\rm S}$$

$$C_{\rm s} = \varepsilon_{\rm Si} A / W$$

$$C_{\text{ox}} = \varepsilon_{\text{ox}} A / x_{\text{ox}}$$

$$C_{\rm G} = C_{\rm ox} C_{\rm s} / (C_{\rm ox} + C_{\rm s})$$



Example 2

Consider example 1. Plot C-V characteristics if V_G is varied from -5 V to +5 V **rapidly**.

$$C_{\rm G}$$
 (-5 V) = $C_{\rm ox}$ =34.7 nF, as before.
 $C_{\rm G}$ ($V_{\rm G}$ = $V_{\rm T}$) = 17 nF, as before.

 $C_{\rm G}(V_{\rm G} > V_{\rm T})$ will continue to reduce (unlike the quasi-steady state condition of example 1). When $V_{\rm G} = 5$ V,

$$5 = \phi_s + 1000 \times 10^{-8} \times 3 \sqrt{\frac{2 \times 1.6 \times 10^{-19} 10^{16}}{10^{-12}}} \phi_s$$
$$= y^2 + 1.69y \text{ where } y^2 = \phi_s$$

Solving for φ_s , we get $\varphi_s=2.38~V$

$$W = 0.545 \mu \text{m}$$
; $C_{\text{s}} = 18.3 \text{ nF}$; $C_{\text{G}} = 12 \text{ nF}$

